

Laser-based Micro-machining for Micro-Optics: The New Frontier for 3D Wafer-scale Manufacturing

Rolando Ferrini

SWISS PHOTONICS

Workshop on Microoptics

Microcity EPFL – Neuchâtel, November 7th, 2022

FEMTOprint SA

Via Industria 3, 6933 Muzzano | Switzerland

www.femtoprint.ch | info@femtoprint.ch



FEMTOprint IN A NUTSHELL

FEMTOprint is a Swiss high-tech **Contract Development & Manufacturing Organization (CDMO)** specialized in high-precision **3D microfabrication in glass.**



01

TRANSPARENT AND ISOTROPIC

02

STABLE AND ELECTRICALLY INSULATING

03

BIOCOMPATIBLE

04

ELEVATED THERMAL PROPERTIES

05

HIGHLY ELASTIC

06

RESISTANT TO CORROSION, ABRASION AND SCRATCHES

07

NEUTRAL TO MAGNETIC FIELDS

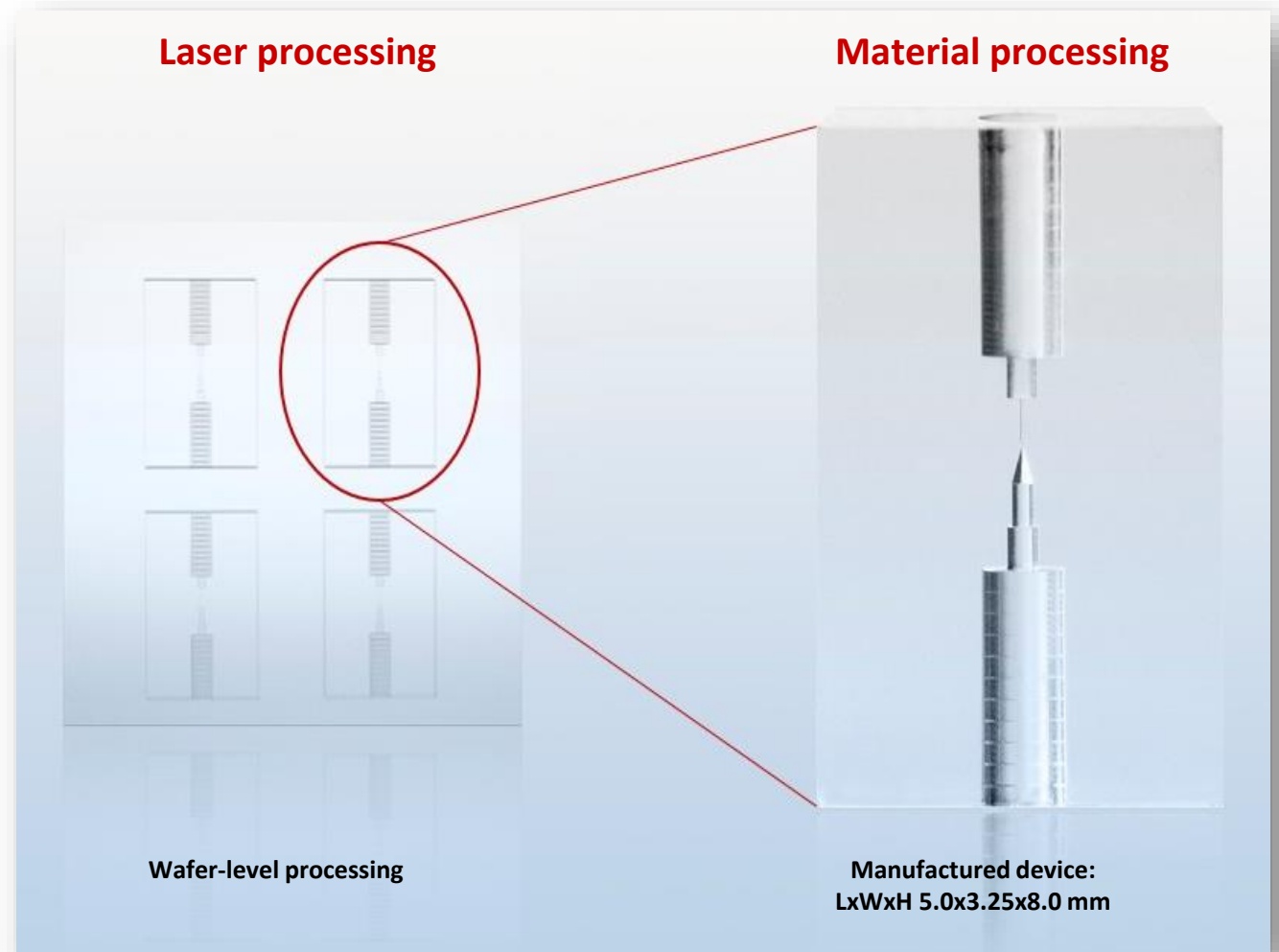


LASER 3D MICROFABRICATION

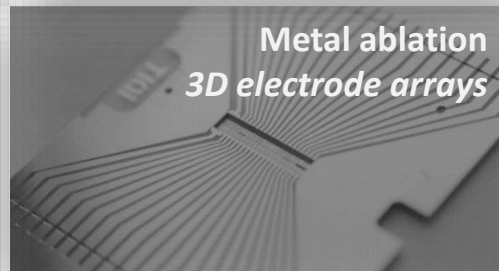
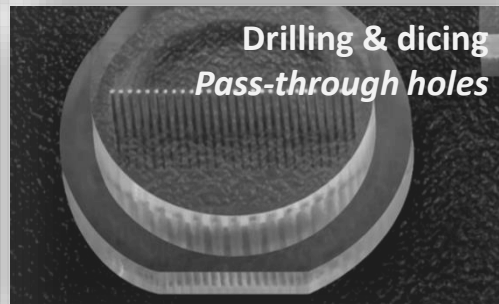
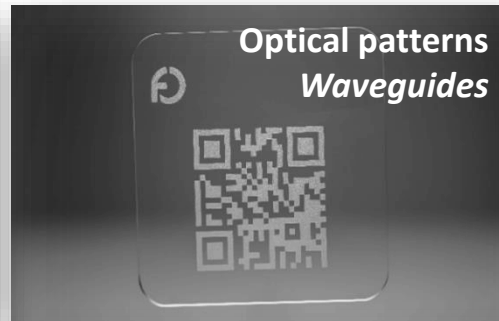
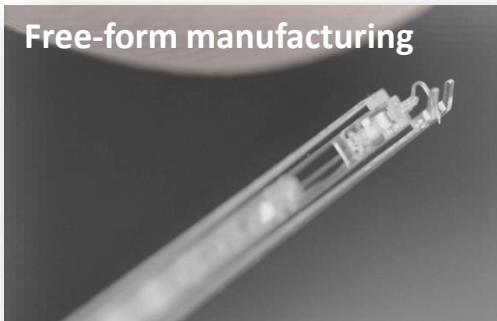
- laser-based microstructuring & material processing
- free-form 2D/3D microprocessing in glass materials

WHY WORKING WITH US

- In-house **unique know-how and capabilities** of glass micro-processing, from proof-of-concept, to pilot and series manufacturing;
- **Vertically integrated**, one-stop shop manufacturing foundry, delivering from single units up to volumes on wafer-level;
- Control over the **entire value chain** and **fast turnaround cycles** in prototyping;
- **ISO 13485:2016** certified for medical devices;
- Suitable for **numerous glass types**: fused silica, fused quartz, borosilicate, aluminosilicate, alkali-free, etc.



CAPABILITIES



PERFORMANCES*

RESOLUTION AND TOLERANCES

- Process resolution $\sim 1 \mu\text{m}$
- XY tolerances $\pm 1 \mu\text{m}$
- Z tolerance $\pm 2 \mu\text{m}$

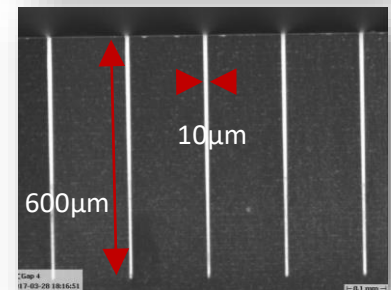
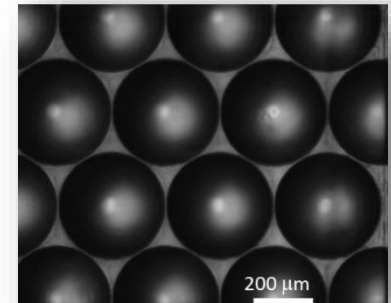
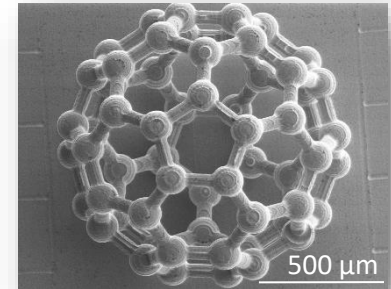
SURFACE QUALITY

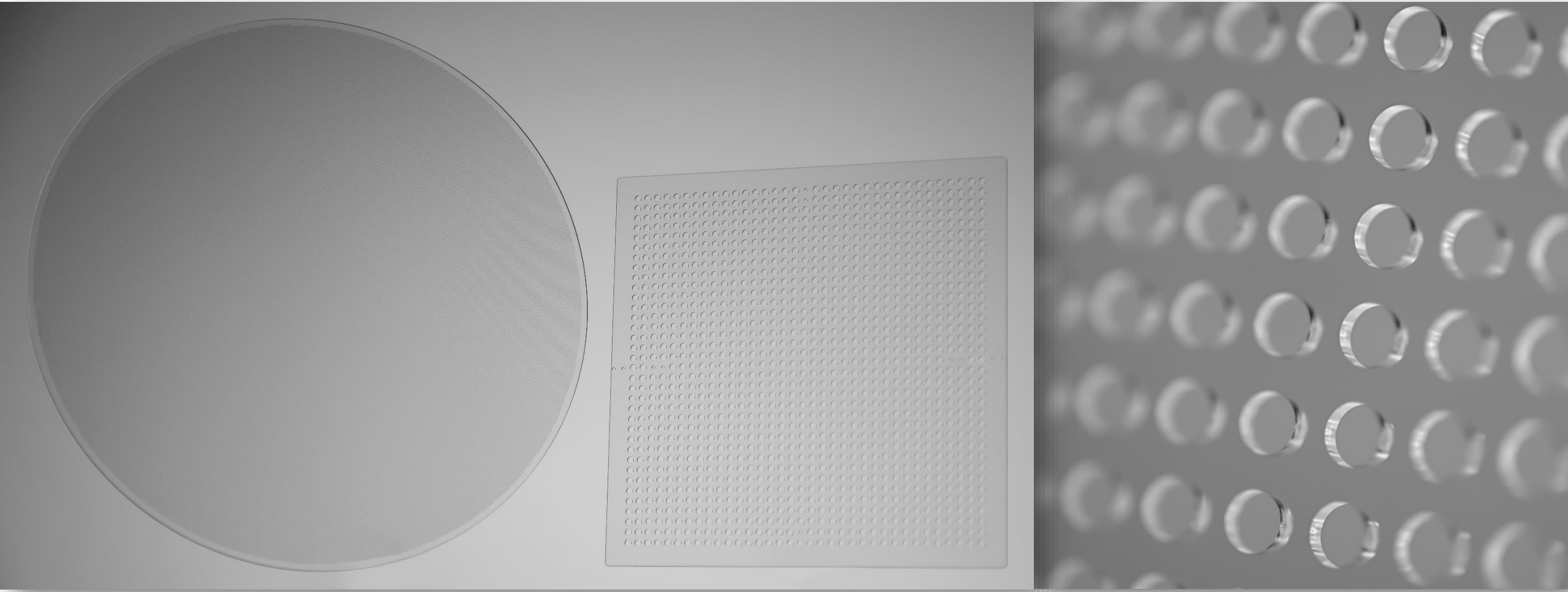
- Patterned surface $Sa \leq 100 \text{ nm}$
- Surface treatment $Sa \leq 10 \text{ nm}$

ASPECT RATIO

- Hole aspect ratio $\geq 1:500$
- Substrate thickness up to 30 mm
- Min. hole diameter $\leq 5 \mu\text{m } \varnothing$
- Sidewall deviation $\leq 0.1^\circ$
- Sidewall roughness $Sa \leq 100 \text{ nm}$

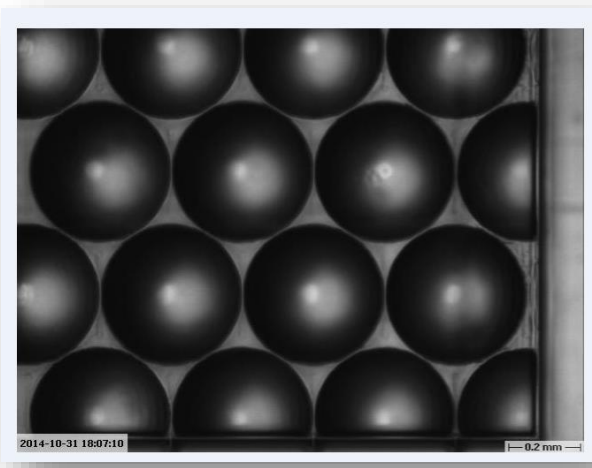
*in SiO₂





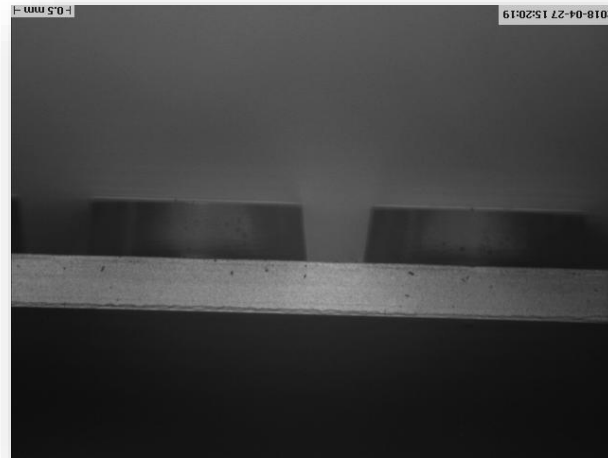
SPHERICAL or ASPHERICAL

**MICRO-LENSES
&
MICRO-LENS ARRAYS (MLAs)**



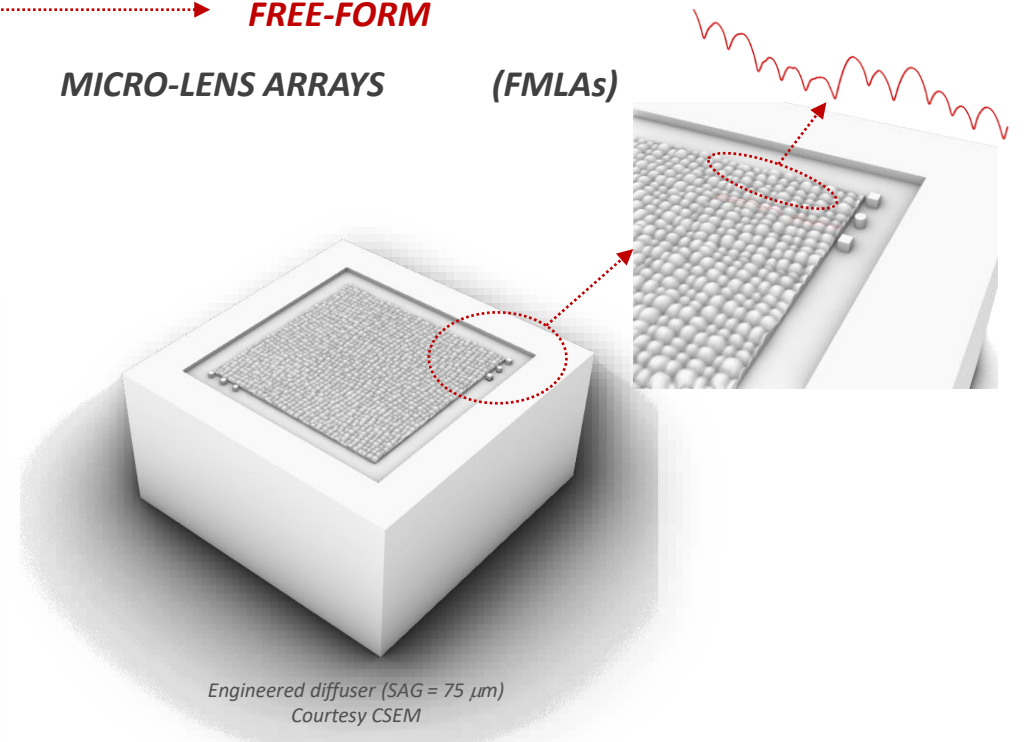
NON-SPHERICAL

MICRO-OPTICAL ARRAYS



FREE-FORM

MICRO-LENS ARRAYS (FMLAs)



Feasibility

Fast prototyping

Pilot manufacturing

Small-to-medium volume
production

ORIGINATION
&
TOOLING

DEVELOPMENT: rapid cycles from concept to prototypes and small-to-medium product series

Enabling large volume production

Flat surfaces

- *Surface roughness*
 $Sa < 10 \text{ nm}$



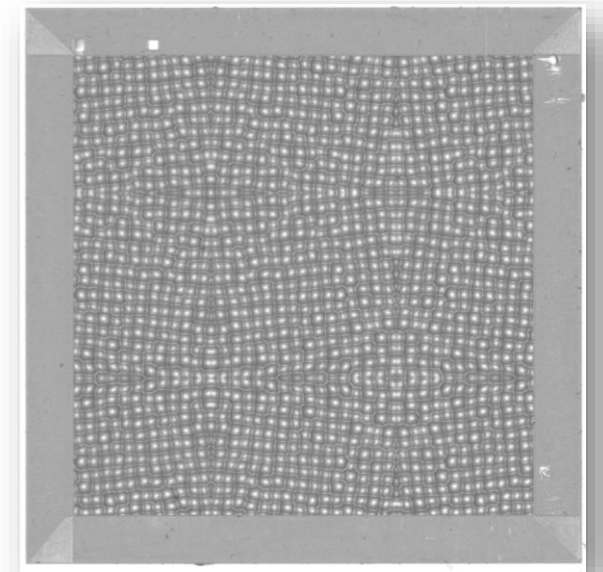
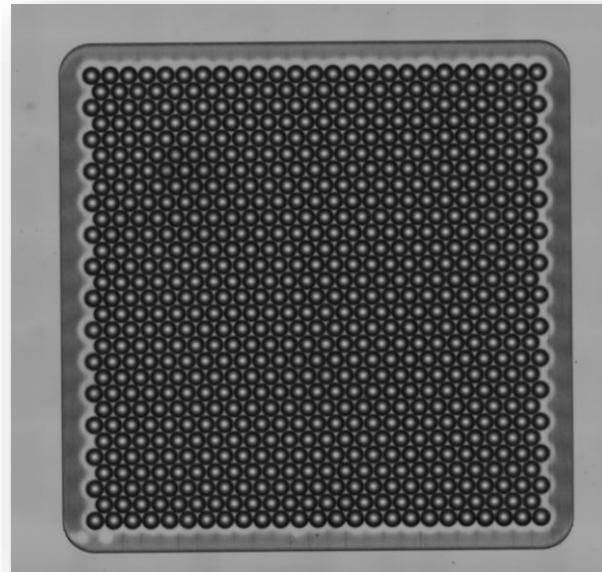
(A)spherical Micro-Lens Arrays

- $Sa \leq 10\text{-}20 \text{ nm}$
- Shape accuracy $\leq 1\text{-}3 \text{ }\mu\text{m}$



Free-form Micro-Lenses Arrays

- $Sa \leq 20 \text{ nm}$
- Shape accuracy $\leq 2\text{-}3 \text{ }\mu\text{m}$

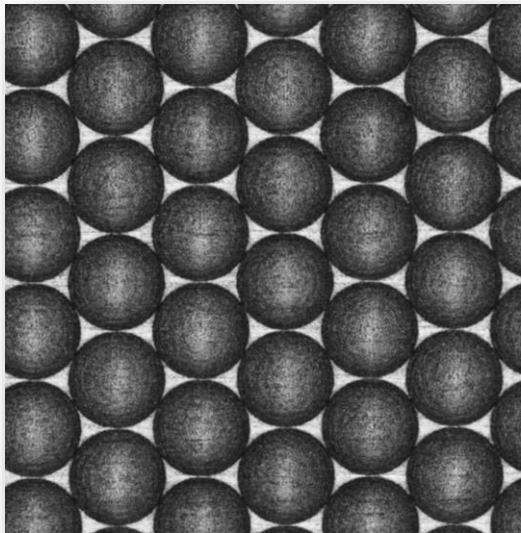


*Innosuisse Project (n. 35418.1 IP-ENG)
Smart LAsEr Manufacturing for precision industry 4.0 (SLAM 4.0)*

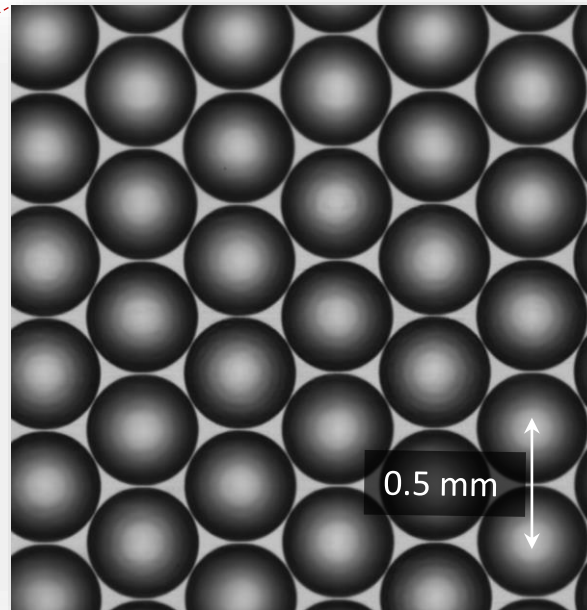
Hexagonal closely packed MLA

100x spherical micro-lenses

- Diameter = 500 μm
- RoC = 650 μm
- SAG = 50 μm



Without surface processing



With surface processing

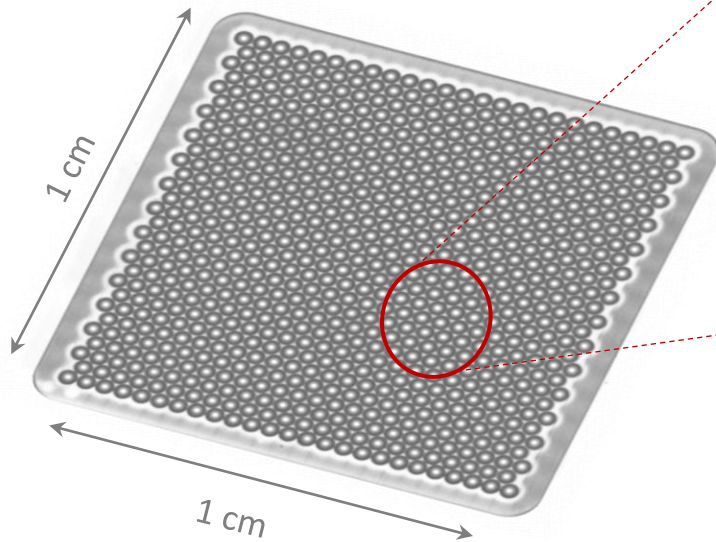
Micro-machined MLAs in Fused Silica

- RoC = $625 \pm 5.0 \mu\text{m}$
- SAG = $51.1 \pm 1.5 \mu\text{m}$
- $Sa = 4.8 \pm 3.3 \text{ nm}$
- Shape accuracy: $< 1.5 \mu\text{m}$

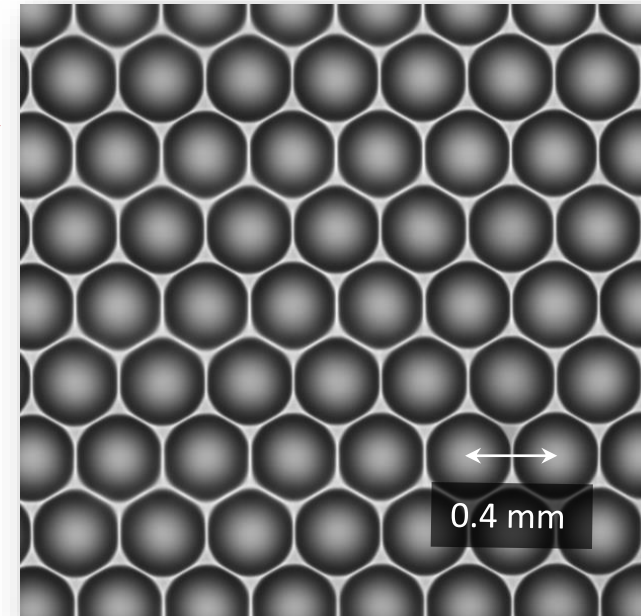
Hexagonal closely packed MLAs

700x spherical micro-lenses

- Diameter = 390 μm
- RoC = 500 μm
- SAG = 39.6 μm



With surface processing

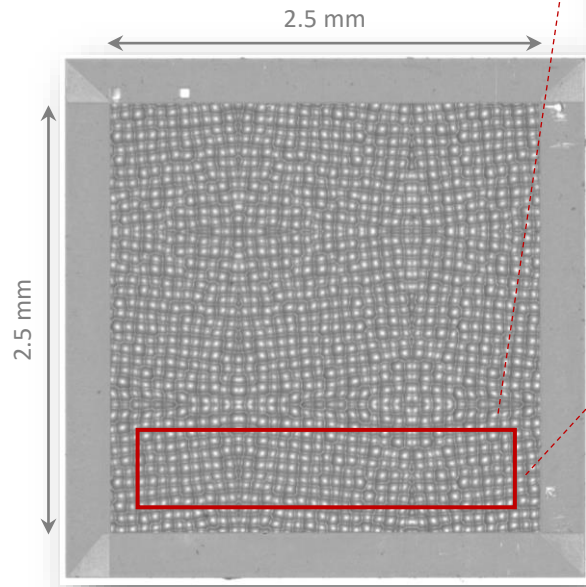


Micro-machined MLAs in Fused Silica

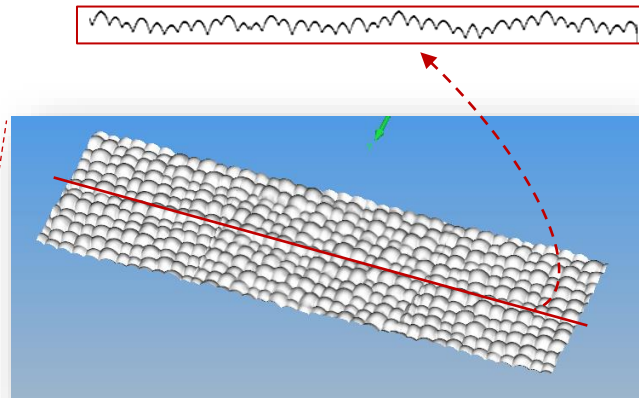
- RoC = 505.5 \pm 12.0 μm
- SAG = 38.9 \pm 0.9 μm
- *Sa* = 7.4 \pm 1.3 nm
- Shape accuracy: < 1.5 μm

Free-form MLA diffuser 1000x free-form micro-lenses

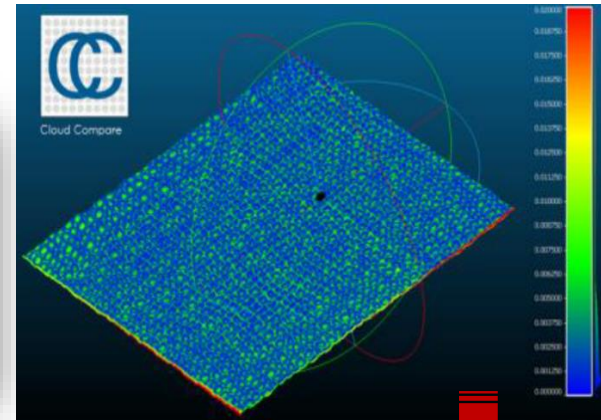
- Diameter = 50-70 μm
- SAG up to 70 μm



Engineered FMLA diffuser – Courtesy CSEM

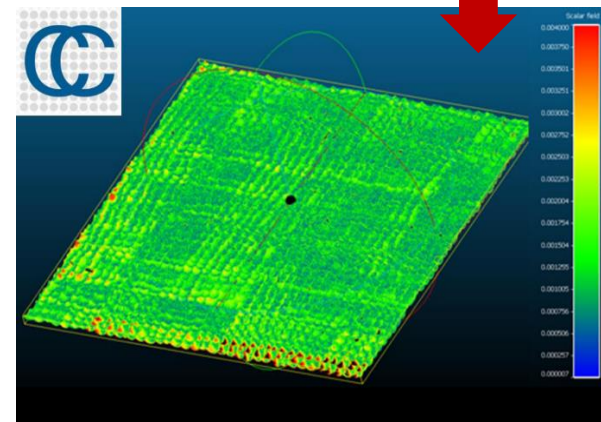


Micro-machined FMLAs in Fused Silica



Without surface processing

- Sa \approx 250 nm
- Avg surf dev: $+0.08 \pm 1.27 \mu\text{m}$



With surface processing

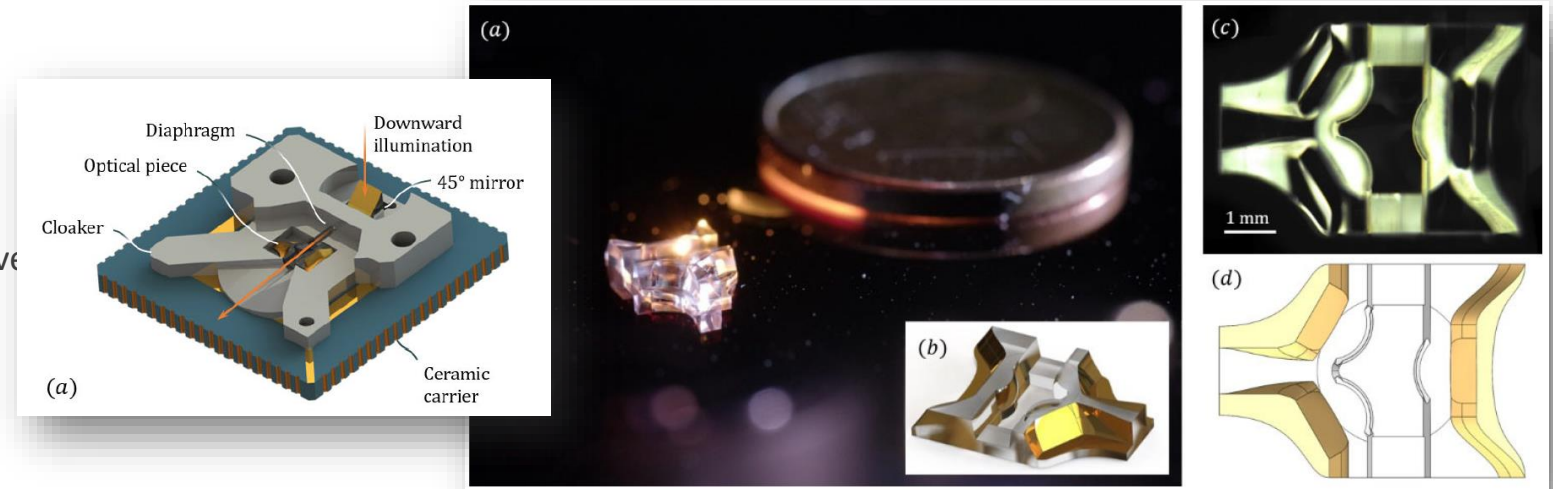
- Sa < 20 nm
- Avg surf dev: $+0.15 \pm 1.71 \mu\text{m}$

APPLICATION

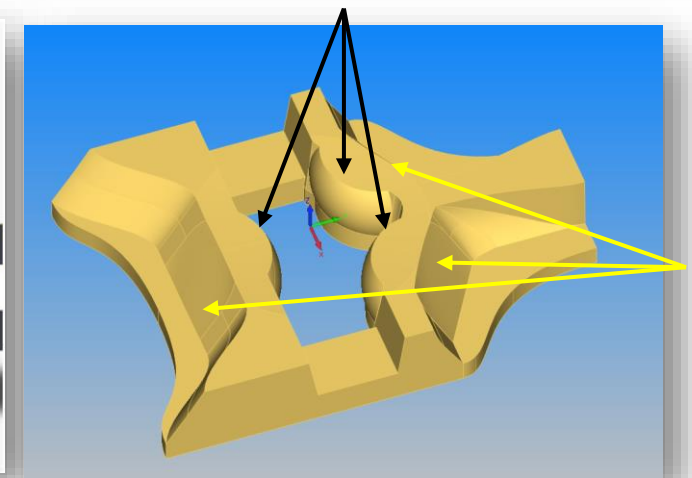
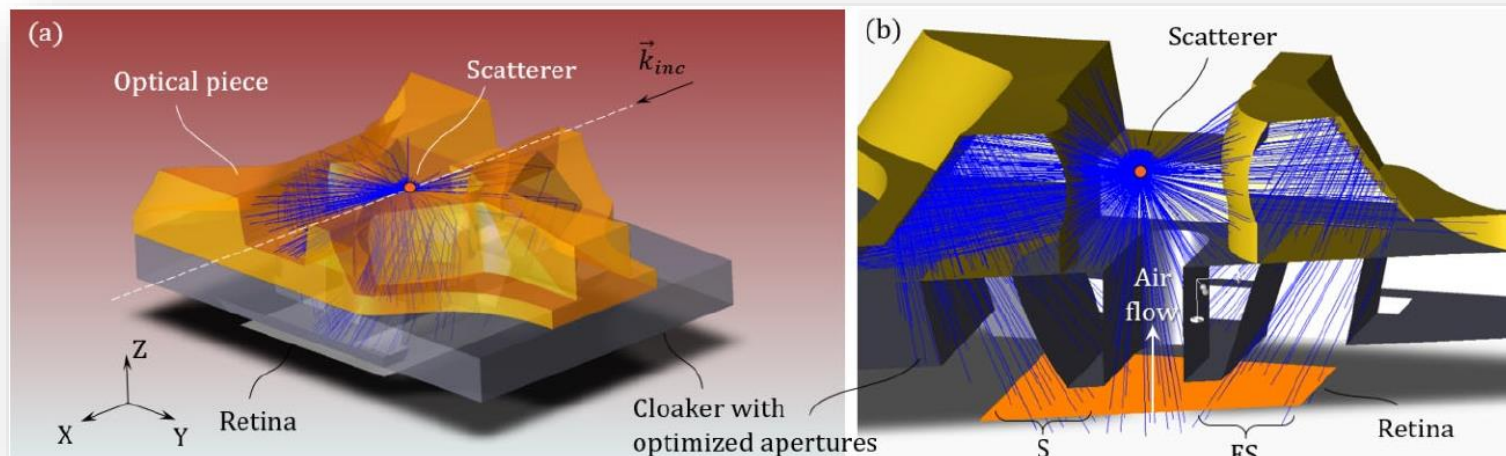
- Air quality monitoring
- Improved sensitivity by the integration of a miniaturized refractive/reflective optical system

USPs

- Monolithic integration of optical functions
- Free-form fabrication in 3D
- Co-packaged miniaturized optics



Slanted diopters

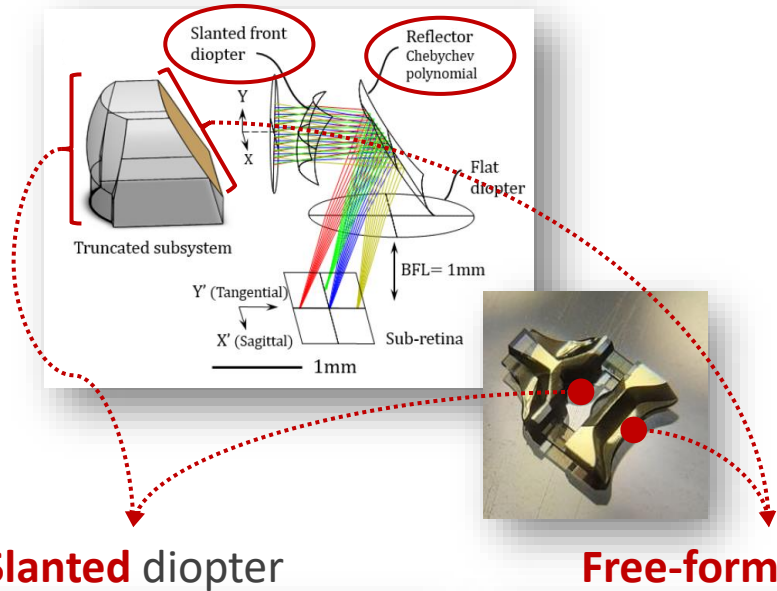


Free-form reflectors

CEA-LETI Minatec & Institut des Nanotechnologies de Lyon.

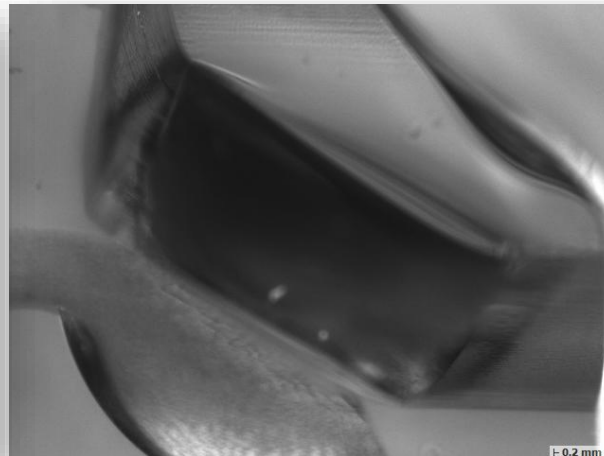
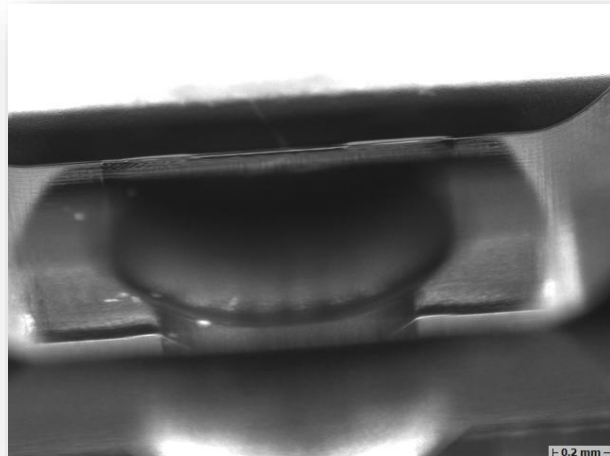
Jobert G. et al. Miniature Optical Particle Counter and Analyzer Involving a Fluidic-Optronic CMOS Chip Coupled with a Millimeter-Sized Glass Optical System. *Sensors* 2021, 21, 3181.

MINIATURIZED 3D OPTICAL SYSTEM

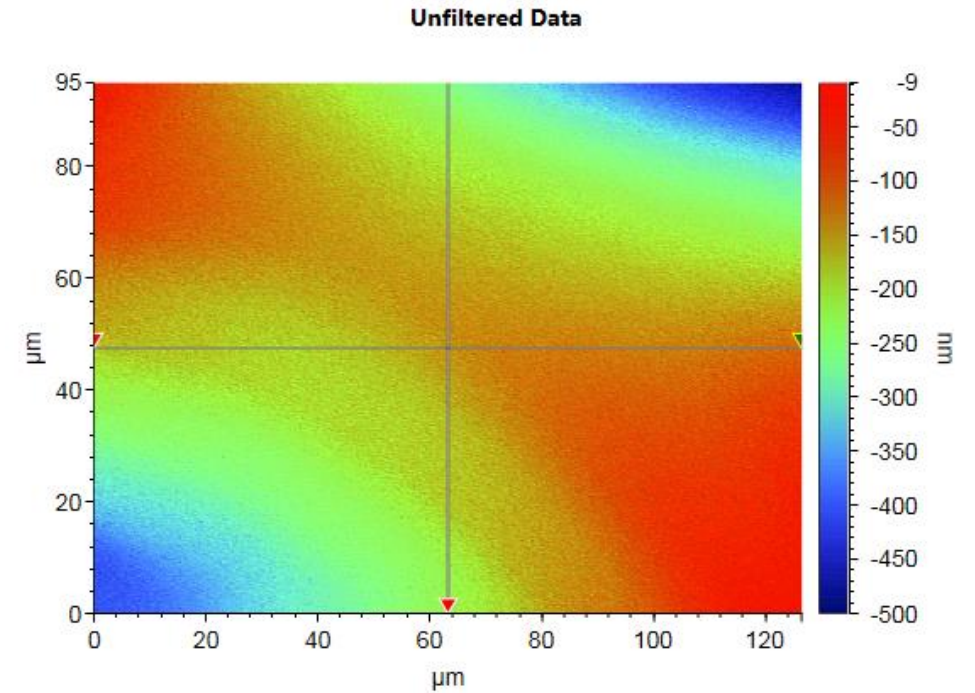


Slanted diopter

Free-form reflector



Interferometric image of the reflector surface



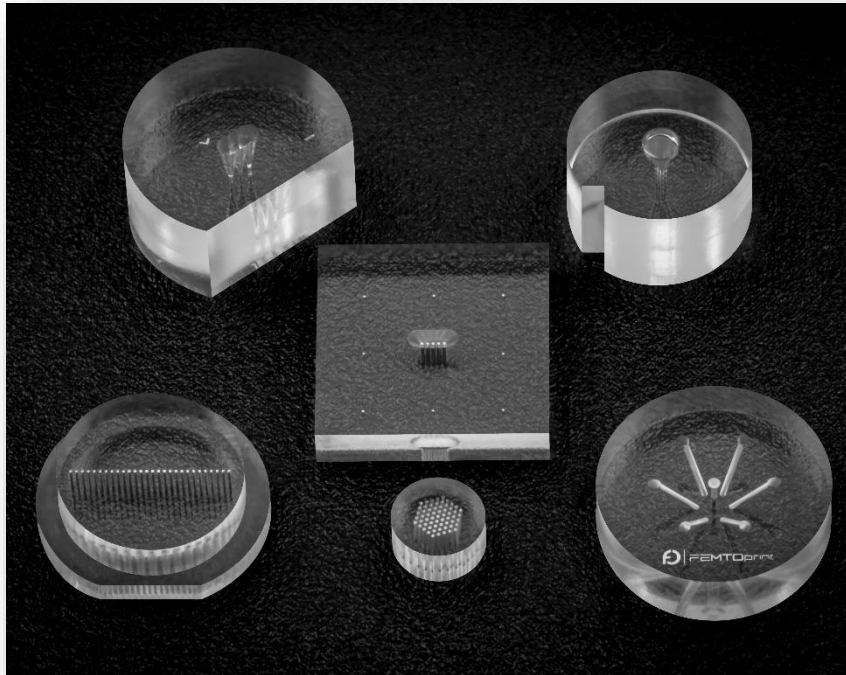
Surface roughness: **Sa = 6nm**

CEA-LETI Minatec & Institut des Nanotechnologies de Lyon.

Jobert G. et al. Miniature Optical Particle Counter and Analyzer Involving a Fluidic-Optronic CMOS Chip Coupled with a Millimeter-Sized Glass Optical System. *Sensors* 2021, 21, 3181.

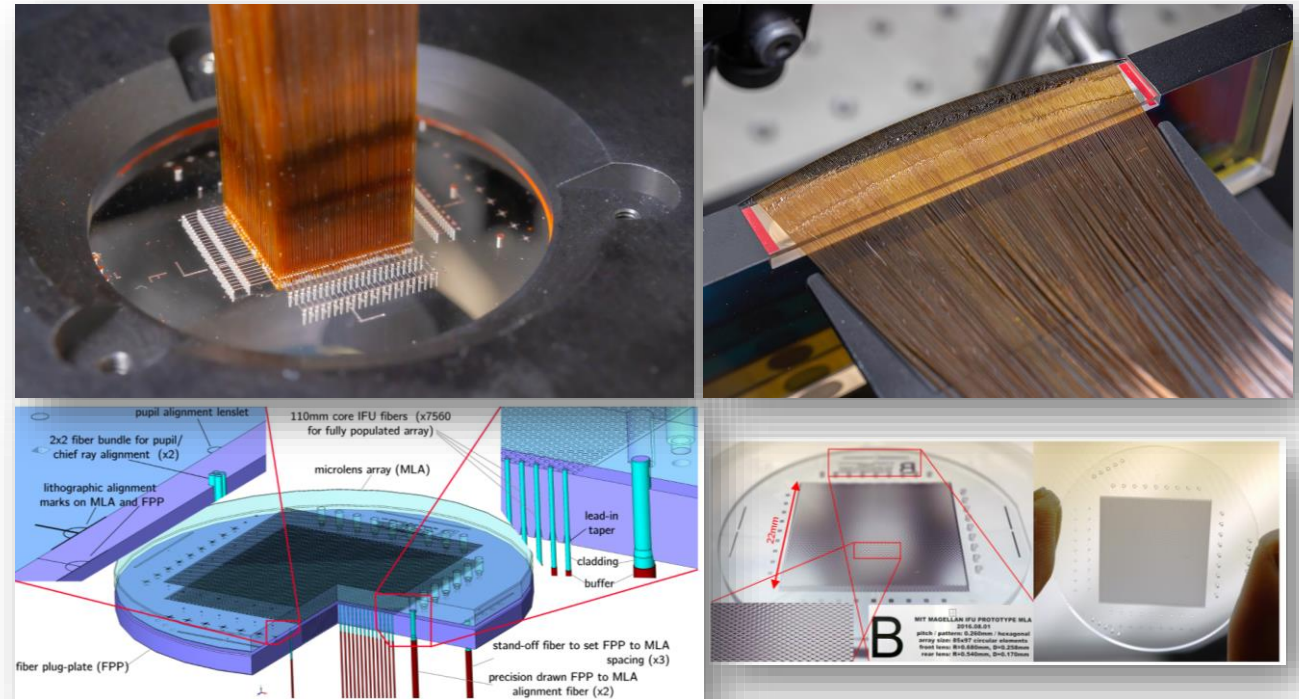
APPLICATION

- 2D fiber arrays & glass ferrules
- High precision fiber-to-chip alignment



APPLICATION

- Integral field spectrograph for astronomical telescope
- High precision 1D and 2D fibre arrays (2400-element) & MLA coupling



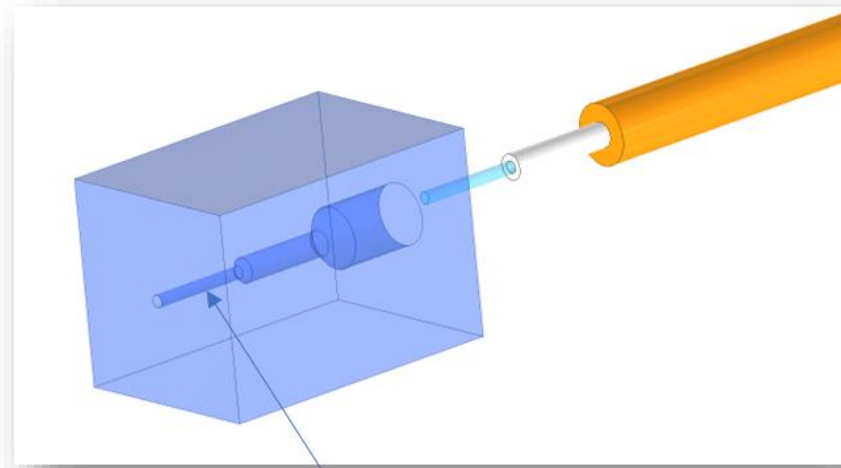
Courtesy of Gábor Fűrész, MIT Kavli Institute for Astrophysics and Space Research

USPs

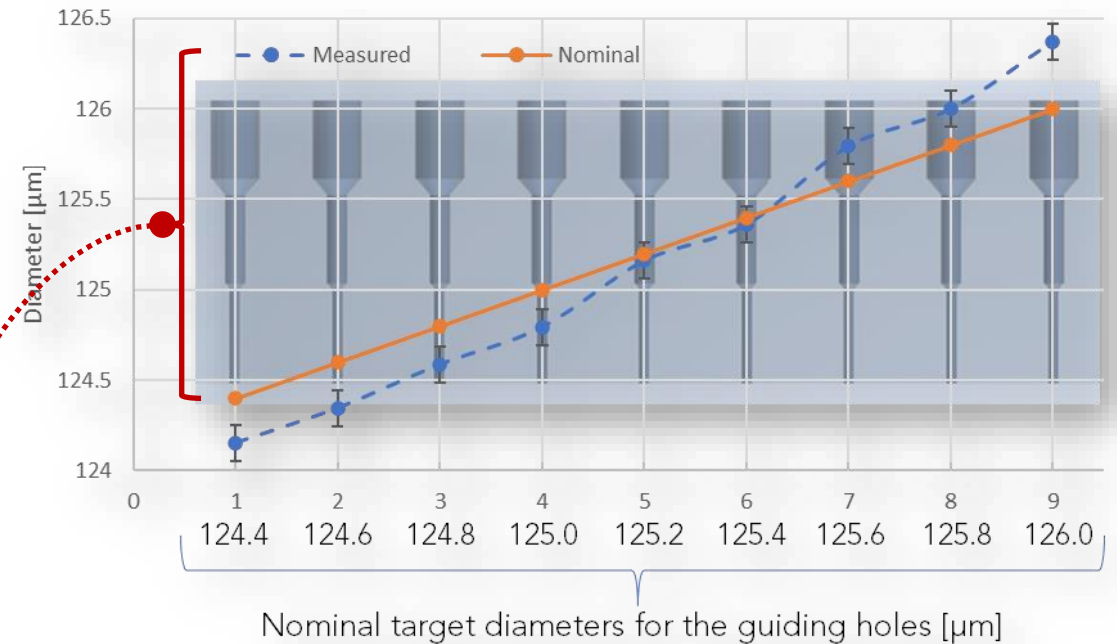
- Thin to thick glass ferrules: mechanical stability & flatness
- Customized hole arrays & additional assembly features
- Precision in hole diameter and positioning < 1 μm

FIBER FERRULES: SUB- μm CONTROL ON HOLE DIAMETER

- Fiber glass ferrules with varying nominal diameters of the guiding section (**steps = 0.2 μm**)
- Mechanical measurements** of the effective diameter of the guiding section



Guiding section (length > 1.5 mm)

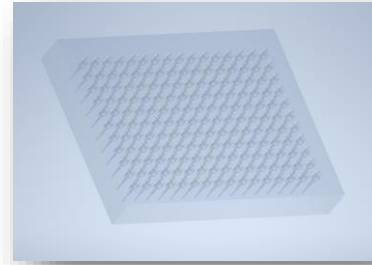


The mechanical measurements confirm that

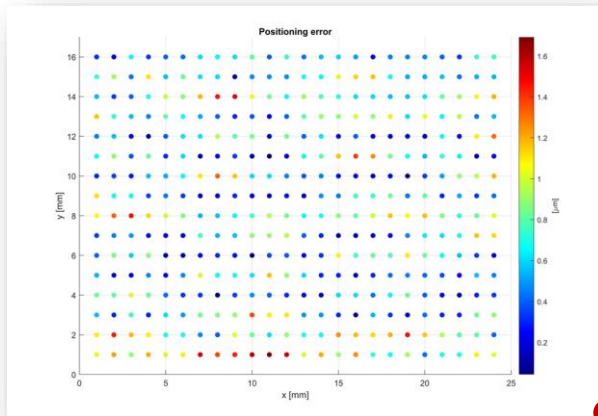
the diameters of the fabricated ferrules correspond to the nominal target values → sub- μm control

FIBER FERRULES: HOLE POSITIONING

- **2D array of 24 x 16 holes**
 - Hole diameter = 125.5 μm

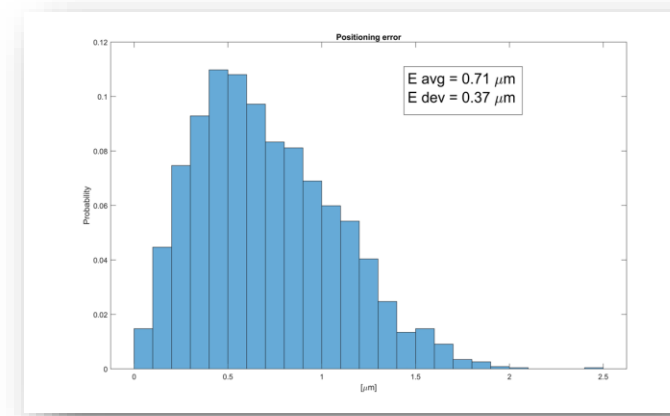


- **5x identical 2D arrays**



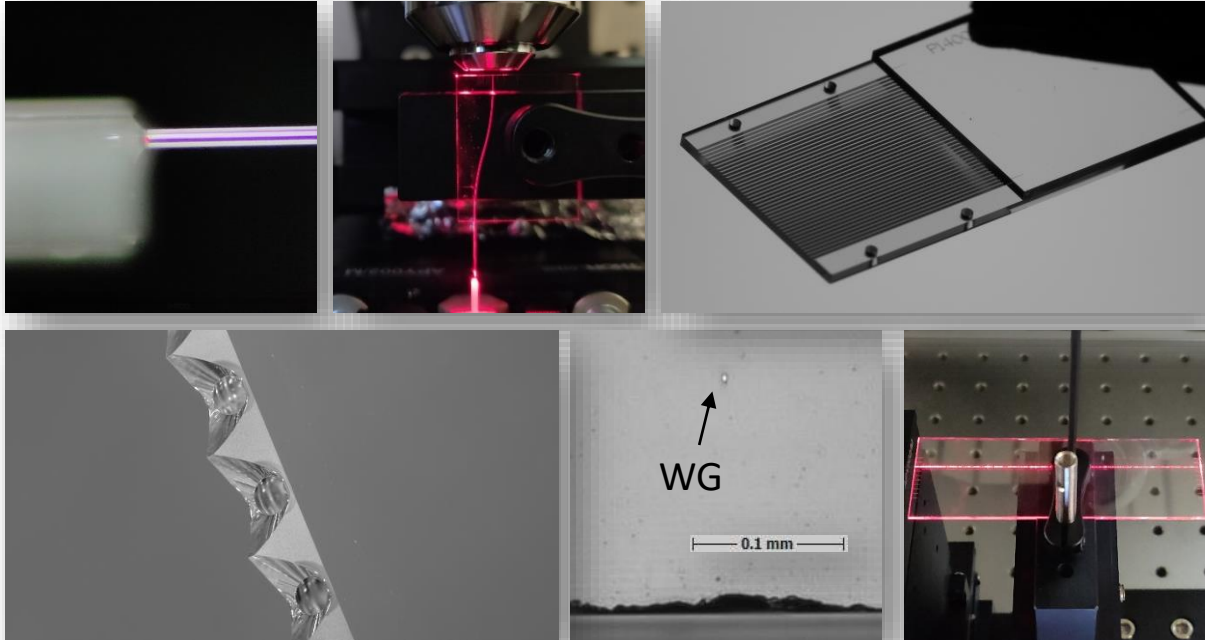
➤ **Hole positioning:** relative error better than the microscope resolution ($\pm 2 \mu\text{m}$)

Hole positioning verified on a single array



- **Average hole positioning error** $\pm 0.7 \mu\text{m}$
- **Standard deviation** $< 0.4 \mu\text{m}$
- **Relative error** better than the microscope resolution ($\pm 2 \mu\text{m}$)

Repeatability verified on multiple arrays

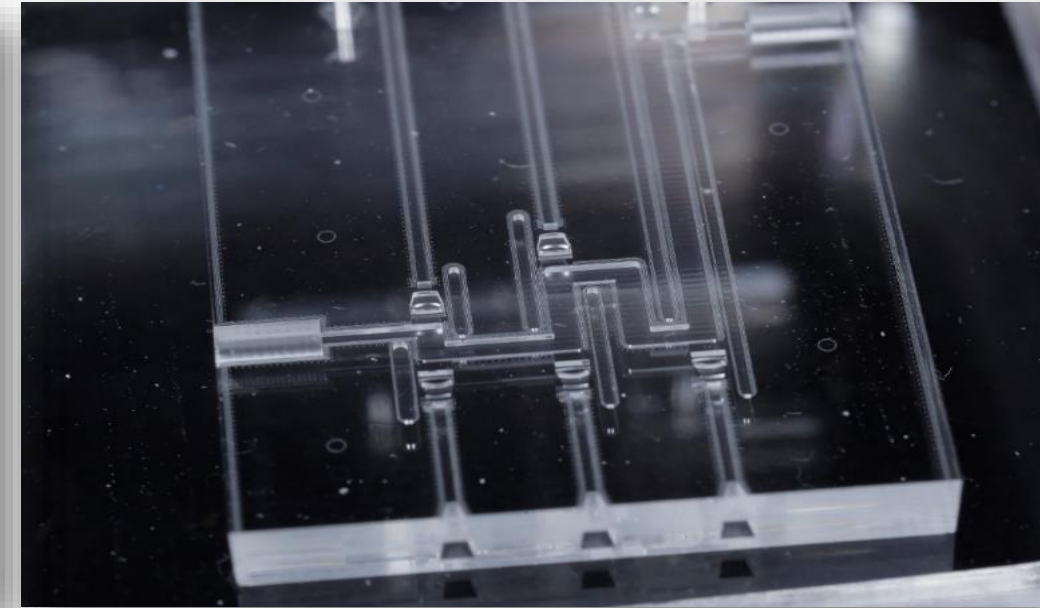
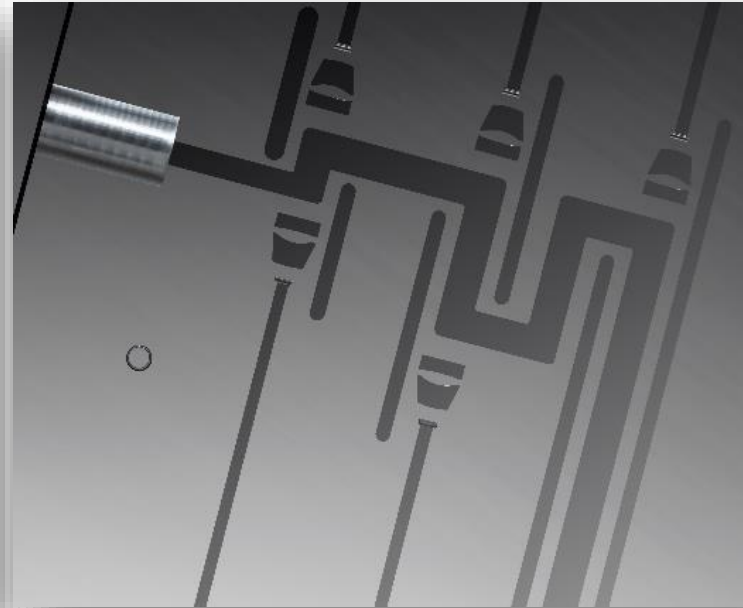
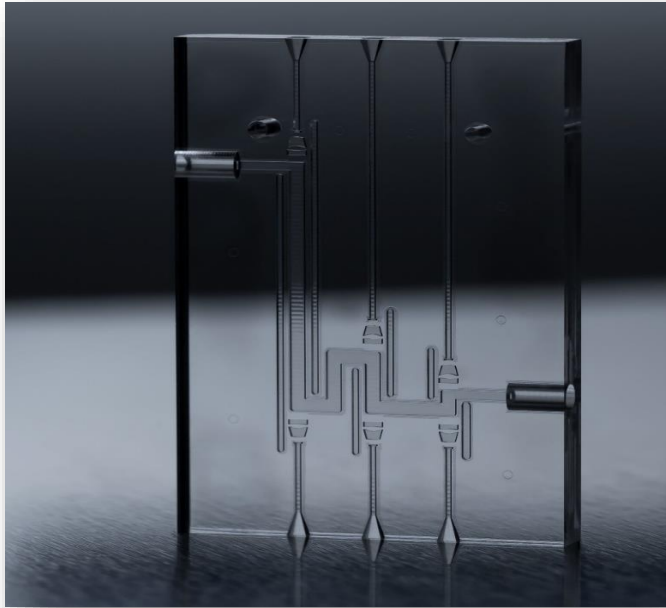


- Single mode & Multi-mode
- Bending in XYZ
- In-bulk termination and tapering
- Combination with ferrules and V-grooves
- Monolithic integration with micro-optical elements
- Alignment markers for assembly & packaging
- Facet polishing for rapid prototyping and characterization

Materials	FS, BF33, EXG
Working λ [nm]	630, 980, 1310, 1550
MFD SM [μm]	3 to 9
Relative positioning	$< \pm 1 \mu\text{m}$
Min. Bending Radius	$\approx 25 \text{ mm}$
Propagation Loss	$< 0.7 \text{ dB/cm}$
Δn	$10^{-2} - 10^{-3}$

USPs

- In-glass photonic wire-bonding
- Monolithic integration of functionalities
- Co-packaged photonic systems



APPLICATION

- Optofluidic Photonic Lab-on-a-Chip
- Monolithically integrated micro-optical system for the optical spectroscopy in a microfluidic structure

USPs

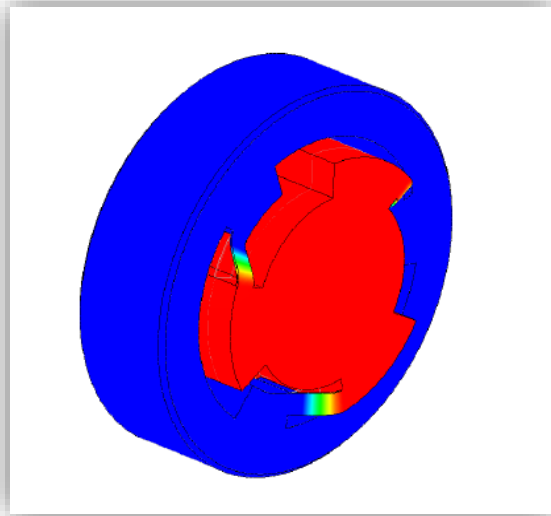
- Combination of optical & non-optical functionalities
- Monolithic integration
- Welding (glass-glass, glass-silicon, etc.)

CEA, DEN, DMRC, University of Montpellier, Marcoule, France.

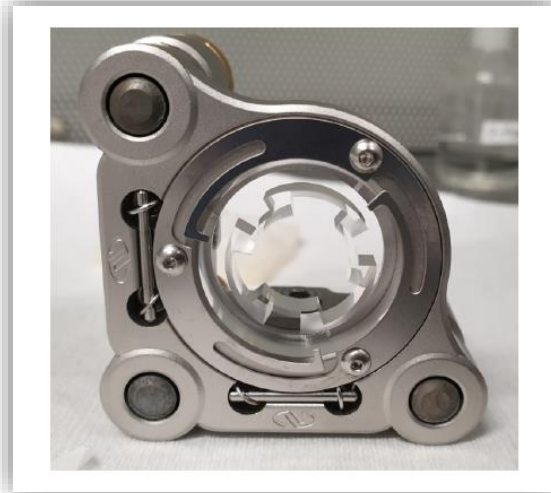
Elodie Mattio et al. Photonic Lab-on-a-Chip analytical systems for nuclear applications: optical performance and UV-Vis-IR material characterization after chemical exposure and gamma irradiation. Journal of Radioanalytical and Nuclear Chemistry (2020) 323:965–973.

APPLICATION

- Optomechanical inertial sensor
- Comparable performance to current sensors used in gravitational wave detectors

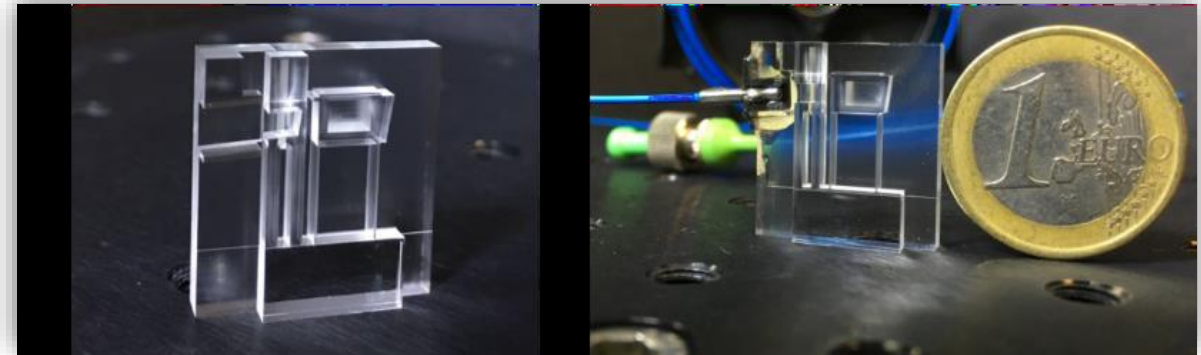


Jonathan Carter - A High Q, Quasi-Monolithic Optomechanical Inertial Sensor (2020)



APPLICATION

- Optomechanical accelerometer
- Tested for high sensitivity broadband acceleration measurements (mechanical oscillator quality factor $\approx 10^5$)



Felipe Guzmán - Compact fully monolithic optomechanical accelerometer (2018) / <https://lasso.engr.tamu.edu/>

USPs

- Exploitation the elastic properties of glass flexures
- Monolithic integration of functionalities
- Introduction of alignment features

WHAT CAN WE DO FOR YOU?

- 3D micro-manufacturing of glass miniaturized & micro- optical components, devices, and systems
- From free-form 2.5D micro-optical elements to 3D miniaturized optical systems
- From feasibility & fast prototyping to pilot manufacturing & volume production
- Origination, Mastering & Tooling for large volume replication (UV imprint, hot embossing, injection molding)
- Monolithically integrated photonic systems, incl. fiber-to-chip coupling solutions for PICs & 3D waveguides (photonic wire bonding)

WHAT CAN YOU DO FOR US?

- Design, Metrology, Functional testing (currently)
- Requests for fast-prototyping, pilot manufacturing, and mastering/tooling services
- Collaboration on the development & manufacturing of
 - miniaturized & micro- optical components, devices, and systems
 - application specific photonic systems
 - multifunctional glass micro-systems

Thank
you!



Via Industria 3
6933 Muzzano
Switzerland



www.femtoprint.ch
info@femtoprint.ch
rolando.ferrini@femtoprint.ch



OPEN POSITIONS

- *R&D Engineer in Optics*
- *Production Engineer*
- *Quality Control Manager*
- ...

www.femtoprint.ch/job-offers